



Workshop of Photonics

FemtoLAB-kit

Laser micromachining
system for laboratory use

System Features

- XYZ high accuracy sample positioning
- Beam delivery and shaping for selected wavelengths*
- Control of entire system through single-window software
- Easily extendable, custom design
- 1 year warranty**

* laser source provided by end user or third party

** extendable upon request

Applications (*depends on end user laser)

- Surface micro- and nano-structuring
- Selective ablation
- Micro-drilling
- 3D direct laser writing
- Refractive index modification
- Dicing and cutting
- Multiphoton polymerization (mPP)

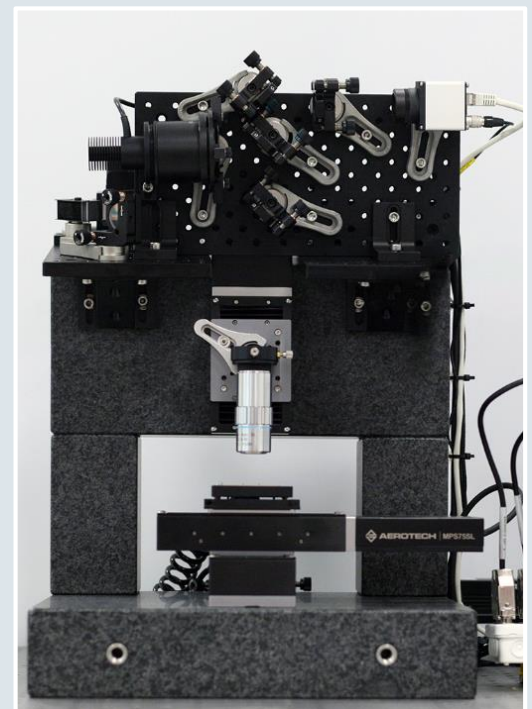



Fig. 1 FemtoLAB kit

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Standard system specifications

Model	Specifications	Value	Unit
XYZ positioning stages			
	Total travel XYZ	50x50x25 (160x160x160*)	mm mm
	Accuracy	±3 (±0,25*)	µm
	Resolution	0,1 (0,001*)	µm
	Max speed	50 (500*)	mm/s
	Max. load	3	kg
	Repeatability	±0,75 (±0,075*)	µm
	XYZ ortogonality	5	arc sec
	In-Position Stability	±0,1 (±0,001*)	µm
	Integrated sample holder with tilting	yes	
	* with ANT-PLUS series		
* parameters may be customized upon request			

XYZ controller



Amplifiers	PVM
Continuous Current	5 A
Peak Current	10 A
Number of Axes	3
Power Supply	240 VAC
Position synchronized output (XY)	dual PSO
Connection to PC	LAN

Motorized power attenuator



Model	ULTRAFast with zero order waveplate
Aperture diameter	15 mm
Antireflection Coating	R < 0.25 %
Time dispersion	t < 4 fs for 100 fs
Polarization Contrast	> 500:1
Automated power calibration	yes

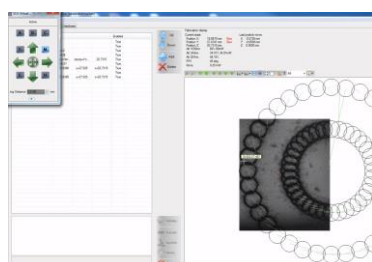
Focusing optics



NA	0.42 or higher
Focal length	4 or smaller mm
Working distance	17* mm
Focus spot size	≈3* μm

* depends on objective selected and customers laser

Machine vision



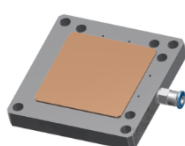
Coaxial lightning	@590 nm
CCD matrix size	1280x1024
Resolution	1 μm
Speed (GigE interface)	15 fps

Beam delivery



Dielectric mirror HR	99,5 %
No dispersion	

Sample holder with vacuum chuck



Porous stone	
Air to vacuum converter	yes

SCA Software (Controls all system devices)



Laser triggering	on/off
Pulse rep. rate	Yes, if laser supports
Power attenuation	Yes
Position stage control	yes
Supported file types	DXF, STL, BMP, PLT, TXT, FAB

SCA manual available online: <http://www.wophotonics.com/products/laser-software/laser-machining-software-sca-professor-v2-5/>

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Optional features

- ↪ Galvanometer scanners
- ↪ Safety enclosure
- ↪ External safety/modulation shutter
- ↪ Autofocus system
- ↪ Spatial light modulator
- ↪ Polarization rotator
- ↪ Polarization converter (Circular, radial or azimuth)
- ↪ your device integration

Principal optical system scheme

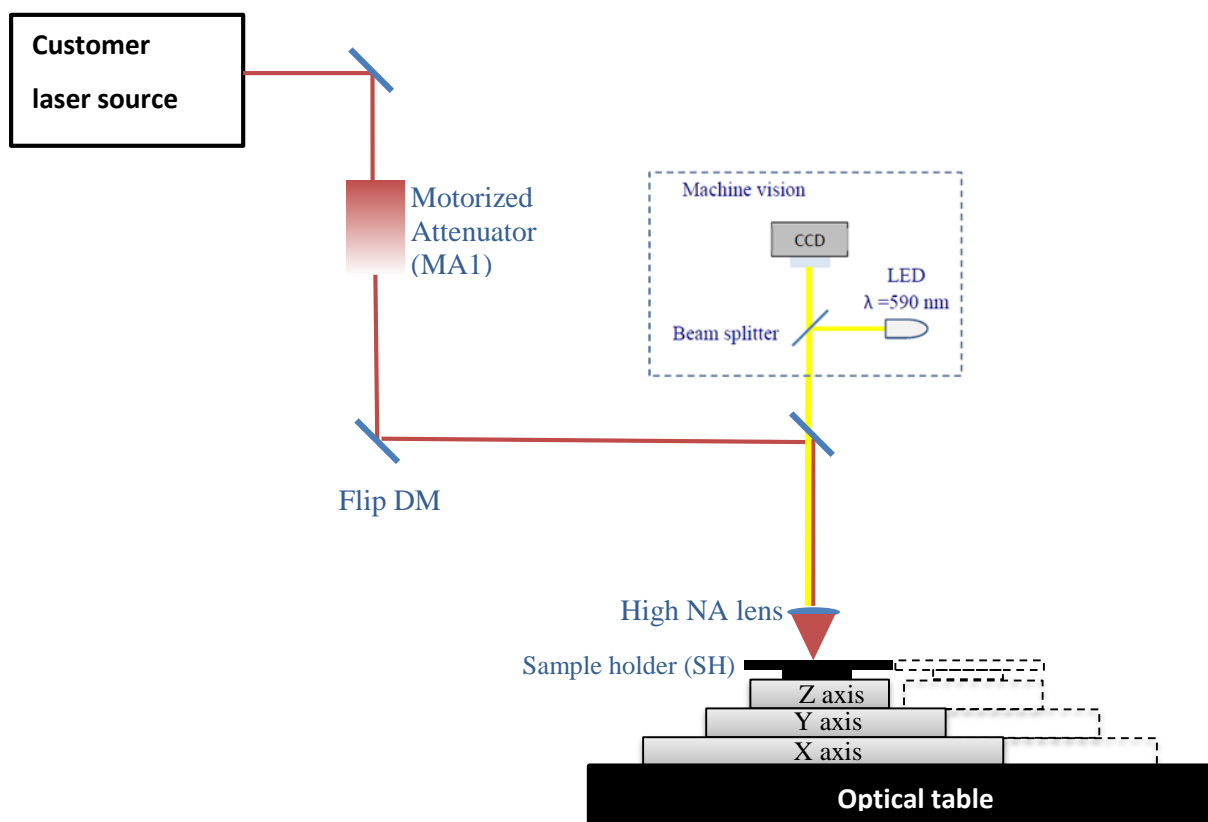


Figure 1 principal optical femtoLAB scheme: motorized attenuator (MA1) for power control, high reflection dielectric mirrors (DM), machine vision, focusing optics, high precision XYZ sample positioning system with integrated sample holder. Optical path designed to minimally widen pulse duration. System will be built on an optical table which ensures stable surface - system footprint is less than 1000x1000 mm (without laser sources).



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Installation and trainings

Installation and trainings are quoted separately upon request.

Test and acceptance

After system installation a test of system parameters can be performed by customer together with Altechna R&D.

System configuration

Main components of the system are listed in quotation. Minor components and exact configuration is determined during system design stage.

Set of spare optical components (mirrors, beam splitters, polarizers) is included in system price.

Delivery Terms

System will be assembled and tuned in Lithuania by Altechna R&D or its subcontractors.

Final system commissioning will take place in at customer site. It may be performed by experienced and trained customer's staff or Altechna R&D or its subcontractors.

Customer is responsible for preparation of installation premises.

Maintenance Terms

All technical issues during the warranty period, arising from proper use of the system should be solved by Altechna R&D or its subcontractors.

Any technical issue should be discussed through Skype or phone and effort should be made from both sides to solve the problem in a distance through consultations.

If remote solving of the problem fails, system should be packed and shipped to Vilnius, Lithuania for repairs. A visit by a service engineer from Altechna R&D or its subcontractors can be quoted on request.

After the warranty period expires, Altechna R&D ensures fee based maintenance for a period of 10 years.

Warranty

The key components of the system bear one year of warranty as a default. Extension of warranty of the system will be quoted on request. Laser beam delivery, focusing and harmonic generator optics shall be treated as consumables, therefore only limited installation warranty is valid for two weeks after installation.

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Fabrication samples

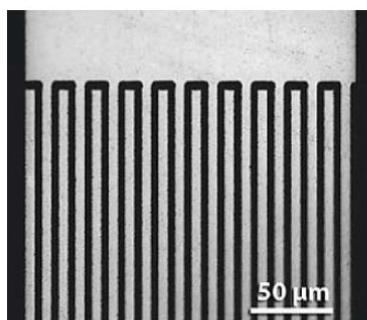


Fig. 1. Selective thin chromium layer ablation from LiNbO_3 crystal surface (Pharos-10W laser, 1030 nm fundamental output).
Courtesy of Workshop of Photonics, Altechna R&D Ltd.

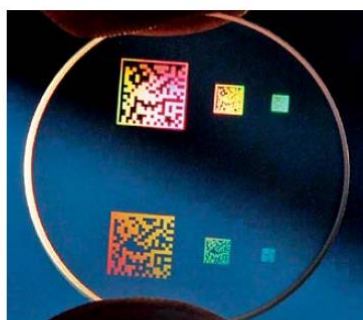


Fig. 2. Sapphire bulk marking
Colors produced by diffraction from printed microscopic structures.
Courtesy of Workshop of Photonics, Altechna R&D Ltd.

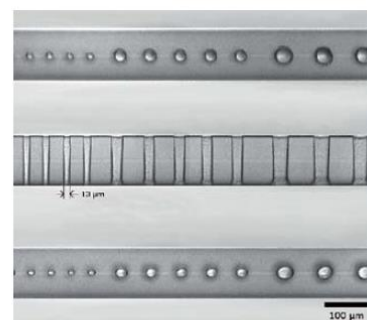


Fig. 3. Example of single mode fibre drilling (Pharos-10W laser, 343 nm third harmonic output).
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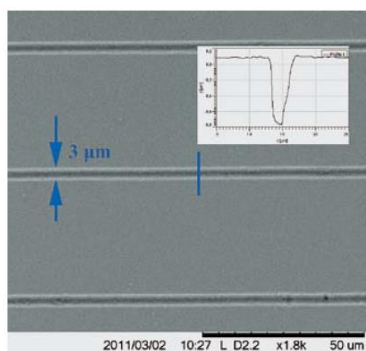


Fig. 4. Machining of grooves in fused silica for micro fluidic applications (Pharos-10W laser, 257 nm).
Courtesy of Workshop of Photonics, Altechna R&D Ltd.

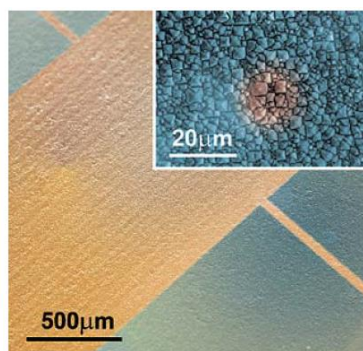


Fig. 5. Contact pathways opened by Pharos laser beam in dielectric SiN_x coated cSi solar cell. Inset – SiN_x layer selectively removed from the front surface of cSi wafer for subsequent Ni deposition.
Courtesy of Workshop of Photonics, Altechna R&D Ltd.

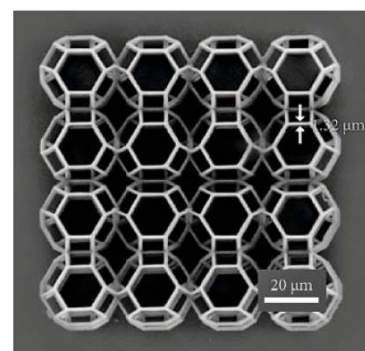


Fig. 6. Cell 3D scaffolding of biocompatible polymer produced by two photon photopolymerisation.
Courtesy of Vilnius University, Laser Research Center.